

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

MASATAKA ITO

Application No.: 10/091,461

Filed: March 7, 2002

For: SOI SUBSTRATE,
ANNEALING METHOD
THEREFOR,
SEMICONDUCTOR DEVICE
HAVING THE SOI
SUBSTRATE, AND METHOD
OF MANUFACTURING THE
SAME

Examiner: S. Isaac

Group Art Unit: 2812

Date: February 20, 2004

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

LETTER TRANSMITTING FORMAL DRAWINGS

Sir:

Transmitted herewith are 2 sheets of formal drawings to be substituted for the corresponding drawing sheets presently on file in the above-identified application.

In the drawings, reference numeral (8) has been changed to (7), for consistency with the specification.

I hereby certify that this correspondence is being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on

February 20, 2004
(Date of Deposit)

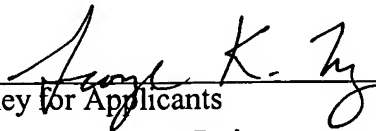
George K. Ng, Reg. No. 54,334
(Name of Attorney for Applicant)

(Name of Attorney)
George K. Ny
Signature

February 20, 2004
Date of Signature

Applicants' undersigned attorney may be reached in our Costa Mesa, California office by telephone at (714) 540-8700. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



Attorney for Applicants
Registration No. 54,334

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